

Notice of References Cited	Application/Control No. 09/735,256		Applicant(s)/Patent Under Reexamination BLOUIN ET AL.	
	Examiner Richard Woo		Art Unit 3629	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,470,229	10-2002	Wang et al.	700/121
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 2000-91178 A	03-2000	Japan	Yamada et al.	-/-
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Eugene S. Meieran, "21st Semiconductor Manufacturing Capabilities" (hereinafter "Manufacturing")12-1999, available at http://www.intel.com/technology/itj/q41998/articles/art_1.htm
	V	Bob Griffin, "Enhanced dataConductor Introduced by Synticity at the International Test Conference 2000 in Atlantic City", 10-2000, available at www.syntricity.com
	W	Gibson et al., "Statistically Based Parametric Yield Prediction for IC"11-1997, 14 pages, IEEE Transactions On Semiconductor Manufacturing, Vol. 10, No. 4.
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.